

	Hits	Search Text
1	246034	substrate.clm.
2	12685	substrat .clm. and (diaphragm r silian\$5 deformabl flexible bendable).clm.
3	1357	(substrate.clm. and (diaphragm resilian\$5 deformable flexible bendable).clm.) and piezo\$8
4	592	(substrate.clm. and (diaphragm resilian\$5 deformable flexible bendable).clm.) and piezo\$8.clm.
5	1	((substrate.clm. and (diaphragm resilian\$5 deformable flexible bendable).clm.) and piezo\$8.clm.) and (x-shap\$5 cross-shap\$5).clm.
6	81	((substrate.clm. and (diaphragm resilian\$5 deformable flexible bendable).clm.) and piezo\$8.clm.) and (four).clm.
7	234	(substrate.clm. and (diaphragm resilian\$5 deformable flexible bendable).clm.) and strain.clm.
8	19	(substrate.clm. and (diaphragm resilian\$5 deformable flexible bendable).clm.) and (strain near3 (two three four)).clm.
9	168	(substrate.clm. and (diaphragm resilian\$5 deformable flexible bendable).clm.) and ((strain resist\$5 gage cell) near3 (two three four)).clm.
10	50	((substrate.clm. and (diaphragm resilian\$5 deformable flexible bendable).clm.) and ((strain resist\$5 gage cell) near3 (two three four)).clm.) and piezo\$8
11	12	(substrate.clm. and (diaphragm resilian\$5 deformable flexible bendable).clm.) and ((strain resist\$5 gage cell) near3 (cross x-shape\$2)).clm.
12	0	((x-shaped x-shape) near3( piezo\$8)).clm.
13	2	((x-shaped x-shape) near3( piezo\$8))
14	30	((four near3 (edge end leg hand finger)) near3( piezo\$8))
15	165	((substrate.clm. and (diaphragm resilian\$5 deformable flexible bendable).clm.) and (edge end leg hand finger) near3( piezo\$8))
16	2	(((substrate.clm. and (diaphragm resilian\$5 deformable flexible bendable).clm.) and (edge end leg hand finger) near3( piezo\$8))) and ((x-shaped x-shape))
17	8509	substrate.clm. sam (diaphragm resilian\$5 deformabl flexibl bendabl ).clm.
18	868	(substrat .clm. same (diaphragm r silian\$5 deformable flexibl bendabl ).clm.) and piezo\$8

	Hits	Search Text
19	368	(substrate.clm. same (diaphragm resilient\$5 deformable flexible bendable).clm.) and piezo\$8.clm.
20	4	((substrate.clm. same (diaphragm resilient\$5 deformable flexible bendable).clm.) and piezo\$8) and (four near2 (edge end leg hand finger)).clm.

L Number	Hits	S arch Text	DB	Time stamp
1	36796	((stress strain shear f rc load) near2 (measur\$5 test\$4 detect\$4 determin\$4 sens\$4 identi\$6 evaluat\$5 estimat\$5 transduc r gauge cell monitor\$4 comput\$5 inspect\$5 calculat\$4).clm.	USPAT; US-PGPUB; EPO; JPO	2003/08/21 14:22
2	1805	((stress strain sh ar force load) near2 (measur\$5 test\$4 detect\$4 d termin\$4 s ns\$4 identi\$6 evaluat\$5 estimat\$5 transducer gauge cell monitor\$4 comput\$5 inspect\$5 calculat\$4).clm.) and substrate.clm.	USPAT; US-PGPUB; EPO; JPO	2003/08/21 14:22
4	209	((((stress strain shear force load) near2 (measur\$5 test\$4 detect\$4 determin\$4 sens\$4 identi\$6 evaluat\$5 estimat\$5 transducer gauge cell monitor\$4 comput\$5 inspect\$5 calculat\$4).clm.) and substrate.clm.) and piezo\$8.clm.	USPAT; US-PGPUB; EPO; JPO	2003/08/21 14:30
7	127	(((((stress strain shear force load) near2 (measur\$5 test\$4 detect\$4 determin\$4 sens\$4 identi\$6 evaluat\$5 estimat\$5 transducer gauge cell monitor\$4 comput\$5 inspect\$5 calculat\$4).clm.) and substrate.clm.) and piezo\$8.clm.) and silicon	USPAT; US-PGPUB; EPO; JPO	2003/08/21 14:25
8	66	(((((stress strain shear force load) near2 (measur\$5 test\$4 detect\$4 determin\$4 sens\$4 identi\$6 evaluat\$5 estimat\$5 transducer gauge cell monitor\$4 comput\$5 inspect\$5 calculat\$4).clm.) and substrate.clm.) and piezo\$8.clm.) and silicon ) and (diaphragm flex\$5 deform\$5 resili\$5).clm.	USPAT; US-PGPUB; EPO; JPO	2003/08/21 14:26
9	24	((((stress strain shear force load) near2 (measur\$5 test\$4 detect\$4 determin\$4 sens\$4 identi\$6 evaluat\$5 estimat\$5 transducer gauge cell monitor\$4 comput\$5 inspect\$5 calculat\$4).clm.) and substrate.clm.) and (piezo\$8 near3 ("x" "X" "+"))	USPAT; US-PGPUB; EPO; JPO	2003/08/21 14:33
10	0	((((stress strain shear force load) near2 (measur\$5 test\$4 detect\$4 determin\$4 sens\$4 identi\$6 evaluat\$5 estimat\$5 transducer gauge cell monitor\$4 comput\$5 inspect\$5 calculat\$4).clm.) and substrate.clm.) and (piezo\$8 near3 (x-shape\$5))	USPAT; US-PGPUB; EPO; JPO	2003/08/21 14:34
11	2	(piezo\$8 near3 (x-shape\$5))	USPAT; US-PGPUB; EPO; JPO	2003/08/21 14:35

4  
 1  
 5  
 100  
 660  
 100 2 3 5 4 6 5 2